

# ACKNOWLEDGEMENT RECEIPT

Electronic Version 1.1

Stylesheet Version v1.1.1

## Title of Invention

## HIGH-PRESSURE PROCESSING CHAMBER FOR A SEMICONDUCTOR WAFER

Submission Type : Information Disclosure  
Statement

Application Number:

10/680783



EFS ID:

99001

Server Response:

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ISVR1	Submission was successfully submitted - Even if Informational or Warning Messages appear below, please do not resubmit this application
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USPTOEFSNot	For assistance with e-filing a patent application, contact the Patent Electronic Business Center: Toll-Free Number:1(866) 217-9197 Website: <a href="http://www.uspto.gov/ebc/">http://www.uspto.gov/ebc/</a>

First Named Applicant: William Jones

Attorney Docket Number:

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File Listing:

Doc. Name	File Name	Size (Bytes)	Date Produced (yyyymmdd)
us-ids	SSI04001-usldst.xml	1797	2005-12-13
us-ids	us-ids.dtd	7763	2005-12-13
us-ids	us-ids.xsl	12026	2005-12-13
package-data	SSI04001-pkda.xml	1706	2005-12-13
package-data	package-data.dtd	27025	2005-12-13
package-data	us-package-data.xsl	19263	2005-12-13
Total files size		69580	

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